

A COATING APPARATUS

Abstract

5 This invention relates to a coating apparatus for
coating a substrate comprising: a chamber; a cathodic arc
source for generating and projecting a plasma beam along
a plasma beam path within the chamber, the projected
plasma crossing a horizontal plane within the chamber; a
10 moveable holder having a planar mounting surface that is
generally parallel to said horizontal plane, the moveable
holder being configured to move the planar mounting
surface relative to the horizontal plane within the
chamber and into the path of the plasma beam to form a
15 plasma coating on the substrate.

(Fig. 1)